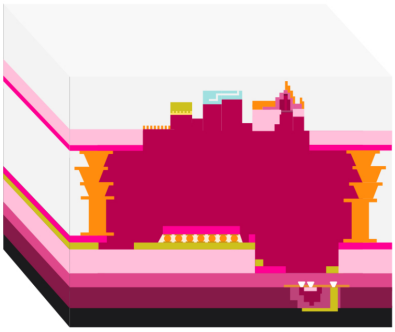
4th DWL Workshop

Sydney 2 Feb 2026



Registration open for: DWL Workshop and Webinar Series

The **4th DWL Workshop**, proudly sponsored by ANFF, will be held on **Monday, February 2, 2026**, at the University of Sydney. Join researchers, scientists, and micro/nanofabrication experts for this one-day event exploring the latest in direct write lithography (DWL) including electron, photon, ion beam and more! Educational webinars will also begin in November 2025.

Want to present at the workshop?

We're calling on researchers, scientists, and experts in micro and nanofabrication to share their insights at the "Innovative Research in Direct Write Lithography Workshop." If you're working on new techniques, applications, or advancements in direct write lithography, we want to hear from you. For details on how to submit your abstract, scan the QR code on the right or click here.

Keynote speaker at the 4th DWL Workshop

Gerald G. Lopez, Ph.D. Director of Operations and Business & Center Associate Director Singh Center for Nanotechnology
University of Pennsylvania | MAEBL Co-Founder and Board Chair | EIPBN Operations Trustee

	Melb, Syd	Adelaide	Perth	Berlin	NY	LA	Topic / Title	Facilitator / Speaker
W1	AEDT 11:00 06.11.25	ACDT 10:30 06.11.25	AWST 08:00 06.11.25	CET 1:00 06.11.25	EST 19:00 05.11.25	PST 16:00 05.11.25	50 Years of Reactive Ion Etching in Microelectronics	Christophe Vallee (University at Albany)
W2*	AEDT 16:00 27.11.25	ACDT 15:30 27.11.25	AWST 13:00 27.11.25	CET 6:00 27.11.25	EST 0:00 27.11.25	PST 21:00 26.11.25	The Physics and Chemistry of Plasma Etching (Part I)	Henri Jansen* (DTU)
W3*	AEDT 16:00 11.12.25	ACDT 15:30 11.12.25	AWST 13:00 11.12.25	CET 6:00 11.12.25	EST 0:00 11.12.25	PST 21:00 10.12.25	The Physics and Chemistry of Plasma Etching (Part II)	Henri Jansen* (DTU)
W4	AEDT 12:00 29.01.26	ACDT 11:30 29.01.26	AWST 09:00 29.01.26	CET 2:00 29.01.26	EST 20:00 28.01.26	PST 17:00 28.01.26	Atomic Mechanisms During Plasma Etching	David Graves (Princeton University)
W5	AEDT tbd .03.26	ACDT tbd .03.26	AWST tbd .03.26	CET tbd .03.26	EST tbd .03.26	PST tbd .03.26	Using the right tool for the job: Comparing ALE, RIE and IBE	Nick Chittock (Oxford Instruments Plasma Technology)
W6	AEST 11:00 08.04.26	ACST 10:30 08.04.26	AWST 9:00 08.04.26	CEST 3:00 08.04.26	EDT 21:00 07.04.26	PDT 18:00 07.04.26	Helicon Double Layer Thruster: A radiofrequency plasma source with many applications	Christine Charles (ANU)

* Please be aware that the webinar you'll be watching is a pre-recorded session. After the presentation, there will be a live Q&A segment.

SCAN TO REGISTER FOR THE EVENT OR CLICK HERE

+ CONTACT

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